Takahiro OHNAKADO

In re Application of:

COMMISSIONER FOR PATENTS

Application No. Filed: For:	09/911,581 July 25, 2001 SI-MOS HIGH-FREQUENCY SEMICONDUCTOR DEVICE AND THE MANUFACTURING METHOD C THE SAME)F
COMMISSIONER FO Washington, D.C. 2		
Sir:	C _L V _O	7
Transmitted herewith	small entity status of this application under 37 CFR 1.27. nsion of Time	,
☐ Applicants claim	small entity status of this application under 37 CFR 1.27.	
Petition for Exten	nsion of Time extension of time under 37 CFR 1.136, the fee for which is \$110.00 (enclosed).	

\boxtimes	Petition	for	Extension	of	Time
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- Applicants petition for a one-month extension of time under 37 CFR 1.136, the fee for which is \$110.00 (enclosed). Applicants believe that no petition for an extension of time is necessary. However, to the extent that such petition is deemed necessary, Applicants hereby petition for a sufficient extension of time to render the present submission timely. Please charge Deposit Account No. 12-1216 for the appropriate petition fee.
- No additional claim fee is required.

☐ Other:

The claim fee has been calculated as shown below:

		-			SMALL	ENTITY		AN A SMALL TITY
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR	EXTRA CLAIMS PRESENT	RATE	ADDIT. CLAIM ; FEE.	RATE	ADDIT. CLAIM FEE
TOTAL		Minus		=	x 9=	\$	x 18=	s
INDEPENDENT		Minus		=	x 42=	\$	x 84=	
☐ FIRST PR	ESENTATION OF MUL	TIPLE CLAIM			+ 140=	\$	+ 280=	\$
				<u> </u>	TOTAL	\$	TOTAL	\$

☐ Pie	ase cnarge my	Deposit Account N	o. 12-1216 in t	the amount of \$

. A duplicate copy of this sheet is attached.

☐ A check in the amount of \$

is attached.

[X] The Commissioner is hereby authorized to charge any deficiencies in the following fees associated with this communication or credit any overpayment to Deposit Account No. 12-1216. A duplicate copy of this sheet is attached.

Any filing fees under 37 CFR 1.16 for the presentation of extra claims.

Any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

Jeffrey **4**. ¶yyand, r_teg. ∧c ŁEYDIG, VOIT &MAYĘR

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Amendment or ROA Transmittal (Revised 9/10/02)



Attorney Docket No. 401308/ASAHINA TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Takahiro OHNAKADO

Application No.

09/911,581

Filed: July 25, 2001

For:

SI-MOS HIGH-FREQUENCY SEMICONDUCTOR DEVICE AND THE MANUFACTURING METHOD OF THE

SAME

Art Unit: 2815

Examiner: N Drew Richards

RESPONSE TO OFFICE ACTION

Commissioner for Patents Washington, D.C. 20231

Dear Sir:

In response to the Office Action dated October 1, 2002, please enter the following amendments and consider the following remarks.

AMENDMENTS

IN THE TITLE:

Replace the title with:

SI-MOS HIGH-FREQUENCY SEMICONDUCTOR DEVICE